Influence of Fe and Al Dopants on the Optical Properties of Zinc Oxide Thin Films Obtained by Spray Pyrolysis

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ABDELMALEK Nadjate¹ and FARH Hichem^{2,3*}

¹ LMSSEF, Larbi ben M'Hidi University, 04000-Oum El Bouaghi, Algeria

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Abstract. An investigation has been done to study the influence of the Fe and Al a ping concentration on the optical properties of zinc oxide thin films. A spray pyrolysis estem was used to obtain ZnO:M films doped with Iron and Aluminum, using zinc acetate dilaydrate cydrated from chlorate and hydrated aluminum chlorate, respectively. The temperature and the concernition were fixed at 450°C and 0.1mol/L, respectively. Our thin films deposed of class bestrate UV-VIS spectrophotometer has been used for the layers characterization. The optic gransmittance spectra showed that the 2% Al dopand improves the optical transmittance in the visible that he Fe dopand. Zinc oxide thin films is the n type semiconductor with direct of the visible that he Fe dopand. Zinc oxide thin films is the n type semiconductor with direct of the visible that he Fe dopand. Zinc oxide thin films in photovoltaic application. But it is urbach energy of ZnO thin films undoped and doped by Iron and Aluminum is varied between 101–12 meV.

1. Introduction

Zinc oxide (ZnO) is one of the most promising II–VI pe schiconductors with an important direct wide band gap (3.3 eV at 300 K) [1-3]. over, Zno is available in abundance, low in cost and is environmentally safe because of its non-terior. The properties of ZnO can be tailored by doping with cationic and anionic dopants like A. Mn, Si, Ag, Cu, Mg and Fe in order to make it suitable for several different applications in electronic, optoelectronic and piezoelectronique devices. [5-7]. Zinc oxide can be sped y Al and e which gives the transparent conductor oxide (TCO) and dilute magnetic semic described. These thin films have been worldwide scientific interest in II-VI. The estigation on DMSs was originally inspired by Ohno et al [8] for discovering the low operature in smagnetism in Mn doped GaAs with Curie temperature (Tc) around 110 K. After the cical predictions of room temperature ferromagnetism (RTFM) in ZnO-based DMS systems by Diet 11, [9-10] a number of groups investigated experimentally this phenomenon subsequently. However, the experimental results on Fe-doped ZnO systems were quite contradictory. Xn. var et al. [11] synthesized the Fe-doped ZnO by using a coprecipitation method and found that it exacts a wak ferromagnetic behavior at room temperature. X. L. Chen et al. [12] reported the pservation of the Fe-doped tetra-needle ZnO whiskers at room temperature. Y. Ahn et al. [13] fabricated the Zn0.97Fe0.003O compounds using the solid state nou. ____, in recent years, transparent conductive oxide TCO is considered the most widely study materials, is given in [14], basics to material physics of TCOs are discussed in [15], some structura investigation of TCOs was made e.g., in [16], preparation of TCOs was discussed in [17] and substitutes for the most popular transparent conducting oxide, namely ITO (indium-tin oxide), are listed in [18]. The optical transmittance measurements reveal that the transparency of ZnO films doped by Fe decreases with the increase of Fe concentration in ZnO [19]. ZnO films doped by Al has an edge over others for being a low cost and earth abundant material, low toxicity, stability in hydrogen plasma, higher optical transmission in UV-Visible range and lower electrical resistivity [20].

In last research, this films deposited several techniques such as chemical vapor deposition, laser ablation deposition and RF magnetron, but these methods require sophisticated equipment. But transparent conducting of zinc oxide thin films (ZnO) [21, 22] were prepared by spray pyrolysis method [22–28]; because this method is simple and inexpensive.

² Department of Material Sciences, University of Tebessa, Tebessa, Algeria

³Active Devices and Materials Laboratory, Oum el Bouaghi University, Algeria

2. Experimental Procedure

In this work, one of the most important experimental parameters in thin films growth is the dopand concentration and substrate temperature, on amorphous glass substrate ZnO thin films were grown at fixed temperature (450°C) and fixed solution concentration (0.1°C).

The precursor solution was prepared by spray pyrolysis technique. In our work, solution was prepared by mixing zinc acetate dihydrate, distilled water; aluminum chlorate and iron chlorate were starting materials, solute, dissolvent and dopand source, respectively. These dopand source for prepared the transparent conductor oxide (TCO) and dilute magnetic semiconductor (DMS) materials respectively.

According to a certain proportion, zinc acetate and dopand source were first dissolved in distilled water at room temperature. The dopand source concentration (Al and Fe) were 0% and 4%. Before doing something, the substrates were cleaned thoroughly. The transmittant and absorption spectra were recorded by an UV-visible spectrometer.

The relation between transmittance and absorption is:

$$T = (1 - R) \cdot \exp(-\alpha . d) \tag{1}$$

T is the transmittance, α is the absorption, d is the thickness, R is the reflectance degligible in our calcule.

The optic band gap of thin films calculated by following relation

$$(\alpha h v)^2 = \alpha (h v - Eg)^{1/2}$$
 (2)

Where:

Eg: Optical gap energy, hv: photon energy.

The formula (3) determining an important parameter that maracterizes the disorder of the material is the Urbach energy (E_{Urb}) By law expression Urbach with the absorption coefficient is of the form:

$$\frac{d(\alpha) = \omega_0 \ln(\frac{h\nu}{E_{Urb}})}{(3)}$$

3. Results and Discosion

Figure 1 resents the transmittance spectra of Aluminum and iron doped zinc oxide at different dopand coventration (0%, 2%, 3% and 4%) with fixed temperature (450°C) and fixed solution consentration (0.1mol/1). The curves showed that the transmittance of thin films decreases with an increase of the spand percentages. This decrease of the transmittance of thin films doped by Aran Fe rown from high atomic percentage may be due to the degradation in the crystalline of the films. The transmittance in the doped samples at 2% to Aluminum is higher than the other thin films doped 10%, 3% and 4% with aluminum. The same observation in the case of the doped samples at 2% to iron is higher than the other thin films doped at 0%, 3% and 4% with iron. The transmittance of thin films of ZnO doped with Aluminum is higher than the transmittance of thin films of ZnO undoped and doped with Iron because the iron atoms is changed the color of the thin films deposited from transparent to brown. But the aluminum atoms keep the transparence of thin films.

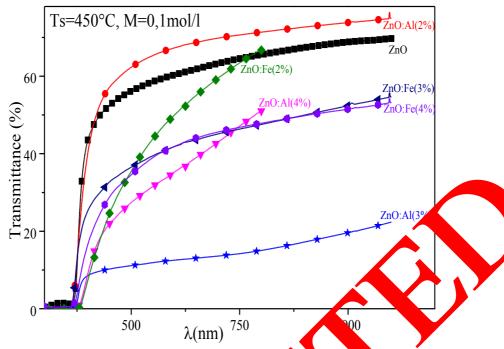


Figure 1. Transmittance spectra of zinc oxide dor d with A. inum and iron.

The values of the transmittance allowed us to determine the optic gap energy and the Urbach energy on our thin zinc oxide films deposited with different do and concentrations, using two formulas (2) and (3) respectively.

The optic gap energy determined by using the type (α hv) ranous with photonic energy (hv), Eg obtained when $(\alpha$ hv)² =0, Figure 2.

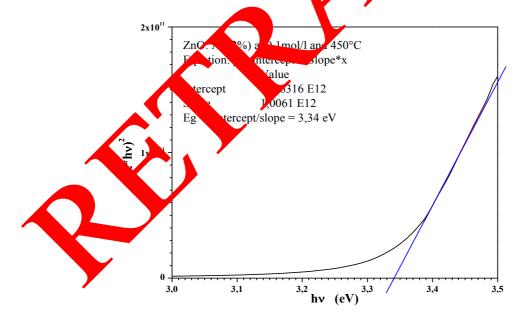


Figure 2. Determined the optic gap energy for ZnO: Al (2%) thin film.

The urbach energy determined by plotting the log (α) various with photonic energy, when urbach energy is the inverse of curve slope, Figure 3.

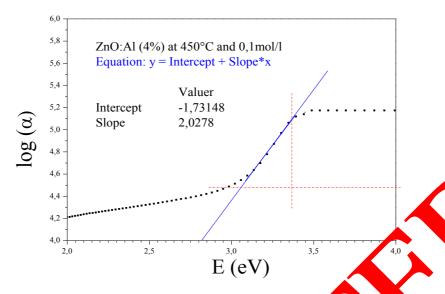


Figure 3. Determined the Urbach energy for ZnO:Al.

The various values of optical gap energy and urbach energy sown in Figure 4 and 5 with different dopand concentrations, we can observe that the nergy gap for Al doping is more significant when the thin films of ZnO doped at 2%. But for iron doping, the large energy gap was presented when the thin films of ZnO doped Fe at 3%.

The optical gap energy to the thin films of zinc oxide dead at 3% i on is 3.317 eV, it is larger than the other thin films doped by Fe at 0% 2% and 4% with he films doped at 0%, 3% and 4% with the energy gap is equal 3.346 eV, it is larger than other thin films doped at 0%, 3% and 4% with Aluminum.

From Figure 4, it is observed that the option gap energy for thin films doped by Al at 2% greater than the other doping rate. But a pecrease fter 2% is determined, this decrease shows that the doping by Al gives thin films the smaller option gap than the ZnO undoped and doped by Fe.

The Urbach energy is a green to the than 4% doping of Al and Fe with respect to the percentage of other dopand

In the Figure 5, it is observed at the Urbach energy for thin layers doped by Fe and Al augmented to 2% then decreased at 5%, but or the percentage 4% the Urbach energy is very greater compared to the other values

In Figure 1 we appresented the growth speed of our thin films. It is observed that the decrease in the growth speed or the Zinc oxide thin films doped with Aluminum up to 2% and then an increase in the percentage 3% and 4%, on the other hand for the Zinc oxide thin films doped by Fe, it is conserved that a increase at the rate 2% then a decrease to 3% then an increase top 4%. This docrease to 2 when a cause to 2 when a server of the explained by several conditions such as: the method of preparation which can cause to 2 when a cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the method of preparation which can cause to 2 when a condition is such as: the condition is such as a condition

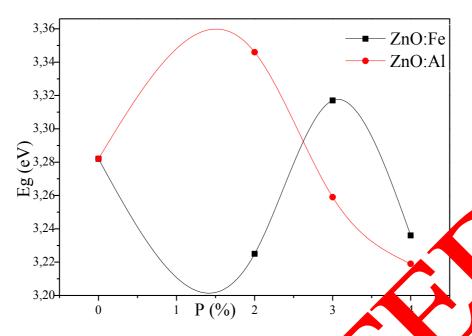


Figure 4. Optical gap energy as a function of the dopart rate in the

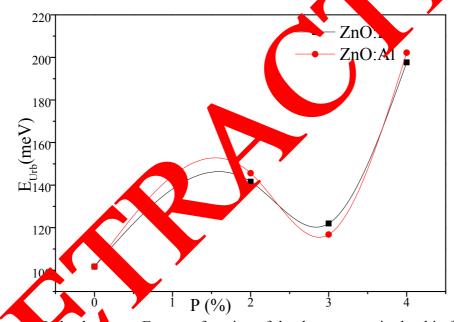


Figure Tbach e ergy E_{Urb} as a function of the dopants rate in the thin films.

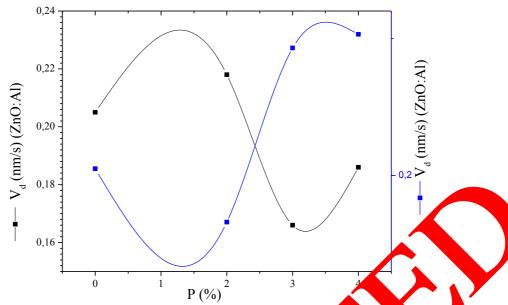


Figure 6. Growth speed as a function of percentage of the departs follows thin layers of ZnO:Al and ZnO:Fe.

Conclusion

In our work, the transparent conductor oxide (TCO) and dilute magnetic semiconductor (DMS) for zinc oxide doped by Aluminum and iron, respectively, ere obtained by spray pyrolysis technique; it is the inexpensive method with the other methods. e transmittance of the ZnO:Al at 2% concentration is very high for other layer at dopand concentration and high optic gap rent energy about 3.35 eV. The optical band gap lie n in ge 3.1-3.35 eV, showing an improvement in transparency with dopand concentration for w yow application at 450°C substrate temperature, whether, for zinc oxide thin films do with aluminum or iron. ZnO thin films are used in various applications due to their high optical transhittance the visible light region about 75% for ZnO: Al (2%). The growth speed varies with in the percentage of dopants of the thin films of ZnO:Al and ZnO:Fe.

References

- [1] Shashidhara, D.; Shrisha, B. V Gopalakrishna, N. K. Archives of Physics Research, 4 (2013) 20-27.
- [2] Ravichandran, K. Rajkurlar, P. V.; Sakthivel, B.; Swaminathan, K.; Chinnappa, L. Ceram. Int. 40 (2017) 12 5-12382
- [3] Jab. B. Ravichandran, K.J. Phys. Chem. Solids, 74 (2013) 841-848.
- [4] Vasant M.; Ravichandran, K.; Jabena Begum, N.; Muruganantham, G.; Snega, S.; Panneerselvan, A.; Kavitha, P. Superlattices Microstructure, 55 (2013) 180–190.
- [5] Carvalho, P.; Sampaio, P.; Azevedo, S.; Vaz, C.; Espinos, J. P.; Teixeira, V.; Carneiro, J. O. Appl. Surf. Sci., 307 (2014) 548–557.
- [6] Su, X.; Jia, Y.; Liu, X.; Wang, J.; Xu, J.; He, X.; Fu C.; Liu, S. Ceram. Inter., 40 (2014) 5307–5311.
- [7] Hassan, M. M.; Ahmed, A. S.; Chaman, M.; Naqvi Khan, A. H.; Azam, A. Mater. Res. Bull. 47 (2012) 3952–3958.
- [8] Ohno, Y.; Young, D. K.; Beschoten, B.; Matsukura, F.; Ohno, H.; Awschalom, D. D. Nature, 402 (1999) 790- 792

- [9] Dietl, T.; Ohno, H.; Matsukura, F.; Cibert, J. Ferrand, D. Science, 287 (2000) 1019-1022.
- [10] Dietl, T. 27th Int. Con. Phys. S.C, Flagstaff, Arizona, USA, July 2004, ed. J. Mendez (AIP Proceeding)
- [11] Xiaojuan, W.; Zhiqiang, W.; Lingling, Z.; Xuan, W.; Hua, Y.; Jinlong, J. Journal of Nanomaterials, 2014 (2014) Article ID 792102, 1-6
- [12] Chen, X.L.; Zhou, Z.W.; Wang, K.; Fan, X.M.; Hu, S.C.; Wang, Y.; Huang, Y. Mater. Res. Bull., 44 (2009) 799-802.
- [13] Ahn, G.Y.; Park, S.I.; Shim, I.B.; Kim, C.S.; Magn, J. Magn. Mater., 282 (2004) 166-169.
- [14] Chopra, K.L.; Major, S.; Pandya, D.K. Transparent conductors, A status review in Solid Films, 102 (1983) 1-46.
- [15] Edwards, P. P.; Porch, A.; Jones, M.O.; Morgan, D. V.; Perks, R. M. Dalton ns. 19 (2004) 2995–3002.
- [16] Kawazoe, H.; Ueda, K. J. Am. Ceram. Soc. 82 (1999) 3330-3336.
- [17] Jarzebski, Z. M. Phys. Stat. Sol. 71 (1982) 13-41.
- [18] Minami, T. Thin Solid Films 516 (2008) 5822–5828.
- [19] Rambu, A.P.; Nica, V.; Dobromir, M. Superlattices and Microstrumes. 59 (2013) 87–96.
- [20] Sengupta, J.; Sahoo, R. K.; Mukherjee, D. Mater. Lett. 83 (2012) 84-37
- [21] Jagadish, C.; Jagadish, C.; Pearton, S. Eds.; Elsevi Oxford, UK, 2006.
- [22] Ellmer, K.; Klein, A.; Rech, B.; Eds.; Springer-Verlag Perlin Germany, 2008.
- [23] Seeber, W. T.; Abou-Helal, M. O.; Barth, D.; Höche, T.; Afify, H. H.; Demian, S. E. Mater. Sci. Semicond. Process. 2 (1999) 45–55.
- [24] Nunes, P.; Malik, A.; Fernand Fritation, F.; Vilarinho, P.; Martins, R. Vacuum 52 (1999) 45–49.
- [25] Nunes, P.; Fernandesa, P., Forta toa, L., Vilarinhob, P.; Martinsa, R. Thin Solid Films 337 (1999) 176–179.
- [26] Mondragón-Suárez (H.; Nes, A.; Castanedo-Pérez, R.; Torres-Delgado, G.; Asomoza, R. Appl. Surf. Sci. 193 (2002) 52–5.
- [27] Gümü, C.; Kend O.M.; Kavak, H.; Ufuktepe, Y. Adv. Mater. 8 (2006) 299–303.
- [28] Jiao, B.C.; Zhao, X.D.; Wei, C.C.; Sun, J.; Huang, Q.; Zhao, Y. Thin Solid Films 520 (2011) 1323–132